

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant(s): Chih-Ming Ke

Application No.: 10/047,266 (CONF 4511)

Filed: 1/14/2002

Title: Reducing photoresist shrinkage via plasma treatment

Attorney Docket No.: 67,200-641

RECEIVED  
CENTRAL FAX CENTERGroup Art Unit:  
1765

MAR 11 2004

Examiner:  
Kin Chan Chen

OFFICIAL

Commissioner for Patents  
Alexandria, VA 22313-1450Certificate of Facsimile Transmission

I hereby certify that this paper (along with any referred to as being attached or enclosed) is being deposited with the United States Patent Office via facsimile no. (703) 872-9313 on the date shown below.

Date: Mar. 11, 2004

kathy dixon

o.k to enter.  
3/18/04 K-cc

Dear Sir:

In response to an Advisory Action mailed March 5, 2004, and as a result of a telephone conference with Examiner Chen on March 11, 2004, please enter the following amendments and consider the following remarks.